

Form PTO-1449

Docket Number 356952000304

Application Number 09/928,194

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

Applicant

K. E. PETERSON et al.

Filing Date August 17, 2001

Group Art Unit To Be Assigned

Mailing Date

September 14, 2001

(Use several sheets if necessary)

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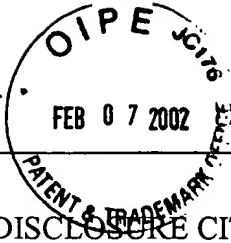
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INFORMATION DISCLOSURE CITATION
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Applicant

Kurt E. PETERSEN et al.

Filing Date August 11, 2001

Group Art Unit 2811

Mailing Date January 11, 2002

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